

## PRESS RELEASE

## Pfeiffer Vacuum expands the HiLobe line of intelligent highperformance Roots pumps

- Diverse applications in the low and medium vacuum range
- Large variety of Roots pumping stations
- Wide nominal pumping speed range up to 6,200 m³/h

Asslar, Germany, September 30, 2020. Pfeiffer Vacuum, one of the world's leading providers of vacuum technology, has expanded its HiLobe series. These Roots pumps are available in a broad spectrum of pumping speeds and applications. The innovative pumps can be used for numerous industrial vacuum applications, including electron beam welding, vacuum furnaces and freeze drying. HiLobe Roots pumps are particularly suited for rapid evacuations (lock chambers or leak detection systems) and as well for general coating applications. With their individual speed control, these vacuum pumps can be adapted to customer-specific requirements.

Compact Roots pumps handle a wide range of nominal pumping speeds up to 6,200 m³/h. Thanks to their powerful drive concept, they achieve around 20 percent shorter pump-down times than conventional Roots pumps. Rapid evacuation also saves costs and increases the efficiency of production systems. The HiLobe series boasts an over 50 percent reduction in maintenance and energy costs compared to conventional Roots pumps. This is due to the use of energy-efficient drives that already meet the future IE4 energy efficiency class. The reduction is also contributed to the optimized rotor geometries of the pumps and by the unique sealing concept. The pumps are hermetically sealed from the atmosphere and have a maximum integral leak rate of 1 · 10<sup>-6</sup> Pa m³/s. Dynamic seals are eliminated, thus making maintenance only necessary every four years.





Cost-intensive water cooling is not necessary since HiLobe Roots pumps can also be operated at ambient temperatures of up to +40 °C using flexible air cooling.

The intelligent interface technology of the HiLobe ensures optimal process adjustment and condition monitoring. This facilitates proactive and efficient operation. The integrated condition monitoring provides information on the state of the vacuum system at all times. Condition monitoring also increases system availability since maintenance and service work can be planned expediently and with foresight to prevent cost-intensive production downtimes. These advantages result in a long service life and maximum operational reliability.

The vacuum pumps can be mounted either vertically or horizontally to suit the existing system. This maximizes pumping speeds and makes more efficient and customized use of the available space at the customer's production facility.

Vacuum pumping stations consist of various pump combinations augmented with suitable components, valves and gauges. Pfeiffer Vacuum has a large variety of Roots pumping stations with different backing pumps, gradations and accessories. Roots pumping stations are used in low and medium vacuum applications and are a reliable solution offering high pumping speeds in the transition range from atmospheric pressure to 10<sup>-3</sup> hPa. The right combination of different vacuum pumps creates a perfect solution for applications in production and research.







Caption: Pfeiffer Vacuum HiLobe



Caption: Pfeiffer Vacuum CombiLine





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## About Pfeiffer Vacuum

Pfeiffer Vacuum (stock exchange symbol PFV, ISIN DE0006916604) is one of the world's leading providers of vacuum solutions. In addition to a full range of hybrid and magnetically levitated turbopumps, the product portfolio comprises backing pumps, leak detectors, measurement and analysis devices, components as well as vacuum chambers and systems. Ever since the invention of the turbopump by Pfeiffer Vacuum, the company has stood for innovative solutions and high-tech products that are used in the Analytics, Industry, Research & Development, Coating and Semiconductor markets. Founded in 1890, Pfeiffer Vacuum is active throughout the world today. The company employs a workforce of some 3,300 people and has more than 20 sales and service companies as well as 10 manufacturing sites worldwide.

For more information, please visit www.pfeiffer-vacuum.com.











